

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yong-Pil Han et al.

Serial No.: 09/498,303

Filed: February 4, 2000

For: HF Vapor Phase Wafer Cleaning and Oxide Etching

Confirmation No. 8629

Group Art Unit: 1763

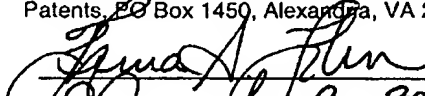
Examiner: T. Dang

COMMISSIONER FOR PATENTS

P. O. BOX 1450

ALEXANDRIA, VIRGINIA 22313-1450

I hereby certify that this correspondence is
being deposited on the date shown below with the
United States Postal Service with sufficient postage
as first class mail, under 37 CFR 1.8(a),
in an envelope addressed to: Commissioner For
Patents, P.O. Box 1450, Alexandria, VA 22313-1450


November 20, 2003

AMENDMENT

This is in response to the Examiner's Action mailed May 21, 2003.

A petition for three-month extension of time accompanies this
amendment.

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims
which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.